

Datasheet: 737496-W16

Macroporous silicon membrane

Etching

| | |
|-------------------|-------------------------------------|
| Type: | lift-off membrane |
| Size: | 6 inch |
| Pitch: | 12 μm square |
| Thickness: | 25 μm membrane thickness |
| Shape: | straight |
| Diameter: | 5-6 μm |

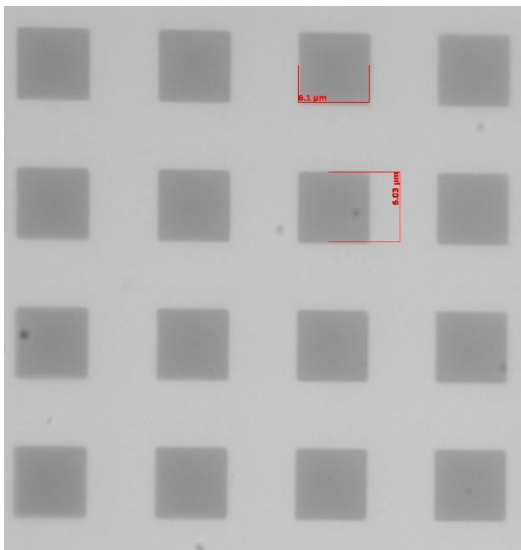
Postprocessing

- Membrane lift-off
- Laserdicing 10.0 mm x 10.0 mm

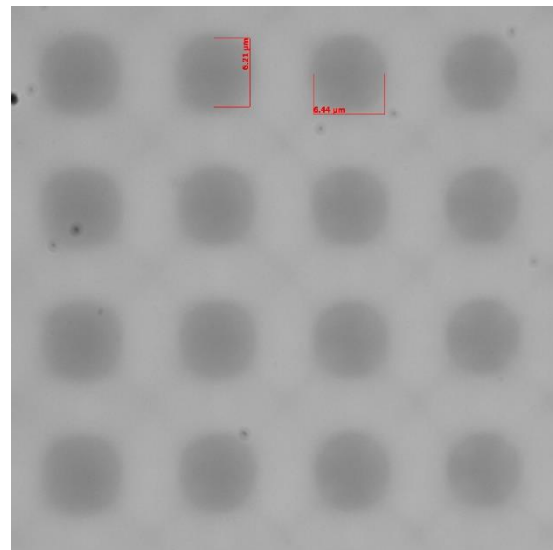
Measurements (generic)

Top view

(front)



(back)



Remarks

- Lifted backsides are sensitive to mechanical handling. Abrasion of silicon nanotips is visible as brown “scratches” on the surface but have minor effect on the underlying pores. We suggest using vacuum tweezers on the front side. Depending on the thickness, flat tips with small diameters are preferred instead of suction cup tips to minimize mechanical stress.
- Please be aware: Membranes <50 μm thickness may flip due to electrostatic forces while opening or closing transport boxes!

09/02/2018 M.Christl

(If not specified separately standard tolerances of $\pm 10\%$ will apply)